

Book reviews

Defect Recognition and Image Processing in Semiconductors and Devices

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This is the proceedings of the Fifth International Conference on "Defect recognition and image processing in semiconductors and devices" which was held in Santander, Spain, 6-10 September 1993. About one hundred participants gave 11 invited lectures and 70 contributions.

This collection is a good review of characterization methods of semiconductor materials and devices. It is organized with eleven chapters discussing the materials (Silicon, III-V and II-VI compounds), the technological process of materials transformation (epitaxy, thermal treatments,...) and the methods of characterization based on images using either the crystalline data given by TEM, STM, SEM, Raman and the electronic data such as photo- and cathodo-luminescence, and Beam Induced Current.

These methods of investigation are in constant evolution due to both the progress of the tools and the imagination of researchers. New approaches for studying the behaviour of devices in greater details continue to emerge. This proceeding volume shows that if many problems have been solved, many others need to be understood in order to improve still further semiconductor technology both in bulk materials and in low dimensional structures.

A particular interest of this book comes from the double viewpoint developed by those contributors who are concerned with the development of both the technological process and the study of semiconductor properties.

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